

ABSTRACT OF THE DISCLOSURE

To make it possible to preferably form a film on  
spacers provided in an airtight container of an  
electron beam apparatus. A method of manufacturing an  
5 electron beam apparatus having an airtight container  
with electron-emitting devices contained therein and  
spacers provided in the airtight container comprises  
the coating step of providing a film on a spacer  
substrate to be the spacers, and is characterized in  
10 that the coating step includes the applying step of  
applying liquid film material by emitting from an  
emitting portion in a predetermined direction to a part  
of a surface of the spacer substrate facing the  
emitting portion.

15

BEST AVAILABLE COPY